<u>X-ray SR monitor</u> (Fresnel Zone Pate (FZP) monitor)

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1. Principle of FZP monitor

2. Setup of FZP monitor

3. Measurement results

4. Summary

- Laser-wire mini workshop 2006, Oxford, England, 3rd July -

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Apparatus of Fresnel Zone Plate (FZP) monitor

• Motivation

- The FZP monitor is aimed to measure the small electron beam size (<10µm) appeared at the ultra low emittance ring like linear-collider damping ring , 3rd generation synchrotron light source and future light sources like ERL (Energy Recovery Linac).
- Features
 - High spatial resolution (<1 μ m)
 - <u>Non-destructive</u> measurement
 - <u>2-dimentional (x,y)</u> beam profiling
 - Real time beam profile mesurement (<1ms)



Monochromated X-ray SR(3.235keV) from bending magnet is used.
 → <u>Reduce the diffraction limit from SR-light.</u>

<u>*Two*</u> Fresnel zone plates (FZPs) are used
 → <u>*The 20 times magnified beam image is obtained at X-CCD.*</u>

Fresnel Zone Plate (FZP)



Spatial resolution is determined by **most outer zone width** of FZPs

Total spatial resolution of FZP monitor

| Parameters | Definition | Resolution(1 σ |
|--|---------------------------------------|-----------------------|
| Diffraction limit (3.235keV) | $\lambda/4\pi\sigma_{ m SR}$ | 0.24) [µm] |
| CZP ($\Delta r_N = 116nm$) | $\sigma_{	ext{czp}} / M_{	ext{czp}}$ | <u>0.55 [µm]</u> |
| MZP ($\Delta r_N = 124$ nm) | σ_{MZP} / (Mczp x Mmzp) | 0.002 [µm] |
| CCD (1 pixel= $24\mu m \times 24\mu m$) | $\sigma_{	ext{ccd}}$ / (Mczp X Mmzp) | 0.35 [µm] |
| Total | | 0.7 [µm] |

 $M_{CZP}\!=1/10$, $M_{MZP}=200,\,M_{\text{CZP}}\;x\;M_{\text{MZP}}=20$

The total spatial resolution is $0.7\mu m$ in R.M.S.

Submicron spatial resolution will be expected on this FZP monitor.





Example of beam image (shutter with 100ms)



Example of beam image (new shutter with 1ms)



Shutter opening time dependence



The measured horizontal beam size was almost 50μ m and was independent of the shutter opening time. On the other hand, the measured vertical beam size was changed from 9μ m to 7μ m by changing the shutter opening time from 4ms shorter.

Measurement of beam position oscillation

In order to search the enhancement of the vertical beam size, we measure the beam position by changing the shutter trigger timing from beam injection timing (shutter opening time fixed with 1ms.)



100Hz beam oscillation made the vertical beam size enhancement

Measured sizes by FZP monitor vs calculation





(Application) 2. Difference between Longitudinal feedback on and off (2006/4/4)



Live mode: no BG subtract TTL pulse 20ms (* Don't remove the effect of 100Hz oscillation)

The large vertical beam profile enhancement was observed by adding longitudinal feedback on. This data is consistent with the measurment of wire scanner at extaction line. (The reason was not understood. Please ask Naito-san)



Remote data taking of FZP monitor



Monitor panel was set on the ATF 1st container.

Now we can continuously take data of FZP monitor on ATF 1st container from April 2006.



Longterm position & size (2006/5/22 - 5/25)

Summary & Future

- We measure the beam size by using FZP monitor at KEK-ATF damping ring. The effect of the unknown 100Hz oscillation was removed on the measurement by using new mechanical shutter with 1ms shutter opening time. After that, the measured vertical beam size of this monitor was less than 7μm.
- ➤ The measured horizontal and vertical beam sizes by FZP monitor and the measured energy spread agreed well with the calculation by assuming the coupling ratio with 0.3~0.6 % with including intra beam scattering .
- The damping time of ATF damping ring with/wihout wiggler were clearly measured by using FZP monitor. The measured damping time agrees well with calculation with each other.
- We can use the FZP monitor as online monitor.

Future plan

- Search the 100Hz vibration source
 - Measure the correlation with B,Q,S power supply data and/or temperature.
 - Plan to add new digital BPM system (Libera) less than 1µm resolution near FZP monitor
- Increase the S/N ratio.
 - apply multi pulses operation (now under going)
- Longterm stability
 - We need to data taking correlated with DCCT ,BPM and other monitor on same data

Multi pulses operation



Thank you



Welcome Kuriki-san (KEK) and Itoh-san (ISSP U-tokyo) to new FZPmonitor group from April 2006.

References



Monochromator

| Crystal | Si (220) |
|----------------------|--|
| Grid interval | d = 0.192 [nm] |
| Bragg angle | $\theta_{\rm B} = 86.35 \deg$ |
| Wave length | $\lambda = d \sin \theta_{\rm B}$ |
| | = 0.383 [nm] |
| Energy resolution | $\frac{\Delta\lambda}{\lambda} = 5.6 \times 10^{-5}$ |

Enough energy resolution for avoiding chromatic abberation of FZP (8 x 10⁻⁴)

Mirror angle drift is reduced less than a few μ rad by adding the water cooling



Fresnel Zone Plates



X-ray CCD

| CCD | Backward full frame |
|-----------------------|-------------------------------------|
| | transfer type |
| Area | 12.29 mm x 12.29 mm |
| Pixel size | 24 µm x 24 µm |
| Quantum effeciency | <90 % (3.24 keV) |
| Cooling | Peltier (-50 C ^o) |
| Dark current | 2 electrons/pixels/sec |
| Scanning speed | 7 frame/sec (Live) 0.5 frame/sec |
| Shutter speed | (Assurian 20ms |

X-ray shutter







C4880-21-24-WD

(made by Hamamatsu K.K)

Performance (Normal mode) at test bench

Horizontal : width of input TTL pulse Vertical : measured shutter width by using laser and PIN photo diode

All view

Expanded view





MZP z-scan



Find the focal point on X-CCD by moving MZP longitudinally.

Alignment strategy



Measurement of magnification



Si monochromator effect

100Hz oscillation の原因を探るべく、Si monochromatorの電源を入れた 状態(on)と切った状態(off)でbeam sizeに変化があるかどうかをshutter opening time (exposure time)を変えながら測定した。



Shutter timeに応じて垂直ビームサイズは同じように変化している。但し、 Si monochromatorのon/offには全く依存していないのがわかる。 →ビームサイズ増加はSi monochromatorでの振動のせいではない。これは summer shutdown中に静電容量センサーで行った振動測定の結果と一致する。

